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# Investigation on repetition-rate electron beam generator for pumping non-chain HF/DF chemical laser\*

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**Abstract :** A 1 Hz repetition-rate electron beam generator is being developed to pump HF/DF chemical laser. The pulse width , peak current and peak voltage of the electron beams are 100ns , 100kA and 450kV , respectively. It uses two diodes , two water-filled pulse forming lines , three laser-triggered switches , a pulse transformer and one set of energy storage capacitors. The primary , secondary and mutual inductances of the pulse transformer are 331nH , 26.5mH and 1.9 $\mu$ H , respectively. The capacitance of each pulse forming line is 8.15nF. Its inductance and impedance are 300nH and 6.2 $\Omega$  , respectively. The breaking factor is 0.3 at 1MV charging voltage. The output energy of a non-chain HF/DF chemical laser pulse is expected to be 250J at 3.8 $\mu$ m.

**Key words :** Repetition-rate electron beams generator ; HF/DF chemical laser ; Pulsed transformer

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With the recent successful application of a single pulse electron beam in pumping high energy laser in the inertial confinement fusion , inertial fusion energy and directional energy laser weapon<sup>[1~5]</sup> , the repetition-rate electron-beam-pumped high energy , high power laser become very interested in these fields today. Thus many laboratories and scientists are involved in developing the repetition-rate electron beam generators to pump gas laser for the laser wavelength from 0.248mm to 10.6 $\mu$ m<sup>[6~9]</sup>. This paper presents our researches on the key technologies of repetition-rate electron beam generator.

## 1 Repetition-rate electron beam generator

The generator shown in Fig. 1 consists of a pulse transformer ( PT ) , pulse forming lines ( PFL1 , PFL2 ) , electron-beam diodes ( D<sub>1</sub> , D<sub>2</sub> ) , primary capacitor ( C<sub>0</sub> ) , laser-triggered gas switches ( G<sub>0</sub> , G<sub>1</sub> , G<sub>2</sub> ) , and a high voltage power. The charging voltage on C<sub>0</sub> is 100kV , the peak voltage on the PFL is 1MV. The design parameters for electron-beams are 0.5MeV , 100kA and 100ns. The expected HF/DF laser energy is 250J at 3.8 $\mu$ m.

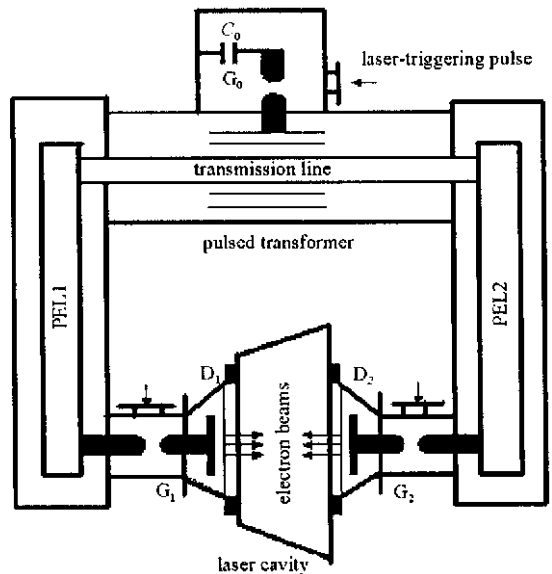


Fig. 1 Cross-sectional view of the repetition-rate electron-beams pumped non-chain HF/DF laser system

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## 2 Structure of the pulse forming line

For the water-filled pulse forming lines , their diameters are calculated on the breaking factors of the PFL according to the J. Martin empirical formula<sup>[10]</sup>. If the diameters of the outline and the inner-line of PFL are  $R$  and  $r$  , when a voltage pulse is applied to the PFL with a peak voltage  $V_{PFL,p}$  , the electric field , breakdown electric field and breaking factors on the inner surface of the outer line of the PFL are defined as

$$E_R^+ = \frac{V_{PFL,p}}{R \ln \frac{R}{r}} , \quad F_R^+ = \frac{0.23\alpha}{t_{eff}^{1/3} A_R^{0.058}} , \quad K^+ = \frac{E_R^+}{F_R^+} \quad (1)$$

respectively , where  $A_R$  is the area of the inner surface of outline ,  $t_{eff} = 0.5 \mu s$  is the charging time of the voltage higher than 63% of the breakdown voltage on the PFL ,  $\alpha$  is the modified factor. It is defined as

$$\alpha = 1 + 0.12 \left( \frac{R/r - 1}{R/r + 1} \right)^{1/2} \quad (2)$$

For the outer surface of the inner line , the parameters are

$$E_r^- = \frac{V_{PFL,p}}{r \ln \frac{R}{r}} , \quad F_r^- = \frac{0.56\alpha}{t_{eff}^{1/3} A_r^{0.069}} , \quad K^- = \frac{E_r^-}{F_r^-}$$

The dependence of  $K^+$  and  $K^-$  on  $r$  and  $\zeta = R/r$  is shown in Fig. 2. The calculation shows that only at  $\zeta = 2.5$  , the two curves overlaid. At  $r = 8 \text{ cm}$  ,  $K^+ = K^- = 0.30$ . It is just the breaking factors of the PFL we chose. Here ,  $\zeta = 2.5$  ,  $r = 8 \text{ cm}$  and  $R = 20 \text{ cm}$ .

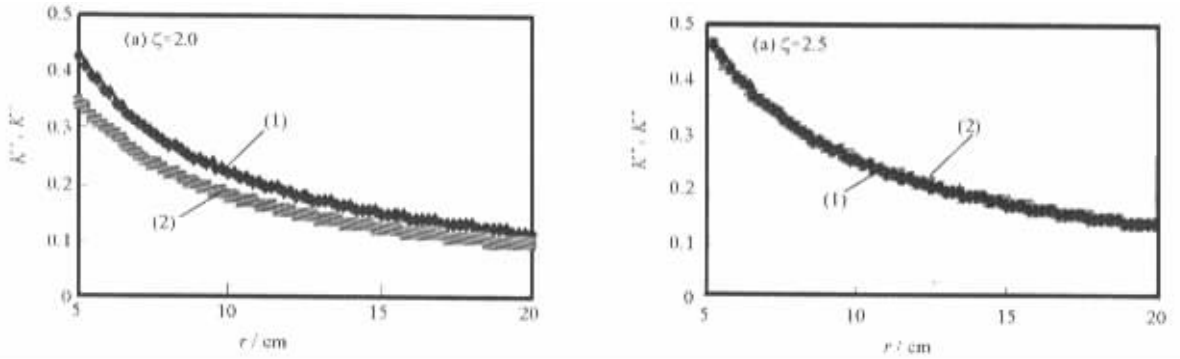


Fig. 2 Breaking factors of the PFL ,  $K^+$  (1) and  $K^-$  (2) versus the radius of the inner liner

For propagation time  $\tau = 100 \text{ ns}$  in PFL , its geometrical length  $L = 1.68 \text{ m}$  as  $\tau = \sqrt{\epsilon_r} \frac{2L}{C}$  , where  $C = 2.998 \times 10^8 \text{ m/s}$  is the velocity of light in vacuum ,  $\epsilon_r = 80$  is the dielectric constant of the de-ionized water. Thus , the capacitance (  $C_{PFL}$  ) , inductance (  $L_{PFL}$  ) and impedance (  $Z_{PFL}$  ) of each PFL are given by the following equations

$$C_{PFL} = \frac{\epsilon_r}{18} \frac{L}{\ln \frac{R}{r}} = 8.15 \text{ nF} , \quad L_{PFL} = \frac{\mu_0}{2\pi} L \ln \frac{R}{r} = 330 \text{ nH} , \quad Z_{PFL} = \frac{60}{\sqrt{\epsilon_r}} \ln \frac{R}{r} = 6.2 \Omega \quad (4)$$

where ,  $\mu_0 = 4\pi \times 10^{-7} \text{ H/m}$  is the magnetic permeability in vacuum the unit of  $L$  is m. All of the parameters of the PFL are listed in table 1.

Table 1 Parameters of each pulse forming line and the parameters of the repetition rate pulsed transformer

$L$	$R$	$r$	$C_{PFL}$	$L_{PFL}$	$Z_{PFL}$	$\tau_1$	$V_{PFL}$	$E_{PFL}$	$Z_{PFL}$	$d_p$	$d_i$	$L_p$	$L_s$	$M$
/m	/m	/m	/nF	/nH	/Ω	/ns	/MV	/kJ	/Ω	/cm	/cm	/nH	/mH	/mH
1.68	0.20	0.08	8.15	100	6.2	100	1	7	6.2	36.6	16	331	26.5	1.9

## 3 Structure of the pulsed transformer

The air core pulsed transformer is shown in Fig. 3.

The windings are composed of 15-turn 2mm thick copper sheet and multi-layer high density polyethylene ( HDPE ) films. The physical performances of this material and other available insulation films for our test

are listed in table 2 . Because the HDPE has a relatively high breakdown field ,  $37.0 \text{ kV/cm}$  and small dissipation factor ,  $0.08 \times 10^{-3}$  at  $1\text{MHz}$  , we chose it as the first candidate material. The  $2\text{mm}$  thick copper sheet is successively wound on a stainless steel cylinder-transmission line of secondary high voltage pulse. HDTL thin film is used as the turn-to-turn insulation material. The widths of the copper sheet of the primary and secondary coils are  $40\text{cm}$  ,  $W_p = W_s = 40\text{cm}$ . The width of HDTE film is  $60\text{cm}$ . The outermost turn of the 15-turn windings is the single primary coil. Other 14 turns are the secondary coils of the pulsed transformer. The diameter of the innermost turn is  $d_i = 16\text{cm}$ . The interval distance between turns is  $5\text{mm}$ . The total thickness of the secondary windings is  $10.3\text{cm}$ . The diameter of the primary single turn is  $d_p = 36.6\text{cm}$ . The total thickness of the transformer windings is  $12\text{cm}$ . The average diameter of the secondary coil is defined as

$$\bar{d}_s = \left( \frac{3 + d_i^2 + 2 \times d_p \times d_i + d_p^2}{6} \right)^{1/2} = 23.4\text{cm} \quad (5)$$

The primary and secondary inductances , the coupling coefficient and mutual inductance of the pulse transformer are get from the following equations<sup>[11,12]</sup>

$$L_p = \frac{\mu_0 \pi}{4} \frac{d_p^2}{W_p} K_L = 331\text{nH} , \quad L_s = \frac{\mu_0 \pi}{4} \frac{d_s^2}{W_s} K_L = 26.5\mu\text{H}$$

$$K = \frac{\bar{d}_s}{d_p} \left( \frac{W_s}{W_p} \right)^{1/2} = 0.64 , \quad M = K \sqrt{L_p L_s} = 1.9\mu\text{H} \quad (6)$$

where ,  $n = 14$  is the turns of the secondary coil ,  $K_L \approx 1$  is the inductance-modified factor<sup>[12]</sup>. All of the parameters of the transformer are listed in table 1.

#### 4 Equivalent circuit model and analysis

The electrical circuit of the system is shown in Fig. 4a.  $C_0$  and  $R$  are the primary capacitor and the charging resistor.  $G_0$  ,  $G_1$  and  $G_2$  are laser-triggered gas switches.  $L_p$  and  $L_s$  are the inductances of the primary and secondary windings of the pulse transformer.  $C_{PFL1}$  and  $C_{PFL2}$  are the capacitances of PFL1 and PFL2.  $C_{T1}$  and  $C_{T2}$  denote the capacitances of the transmission lines of the secondary high voltage pulse on the left side and right side , respectively.  $C_{PT}$  is the total distributed capacitance of the copper sheets in the pulsed transformer.  $Z_{D1}$  and  $Z_{D2}$  are the impedances of the two field-emission diodes.

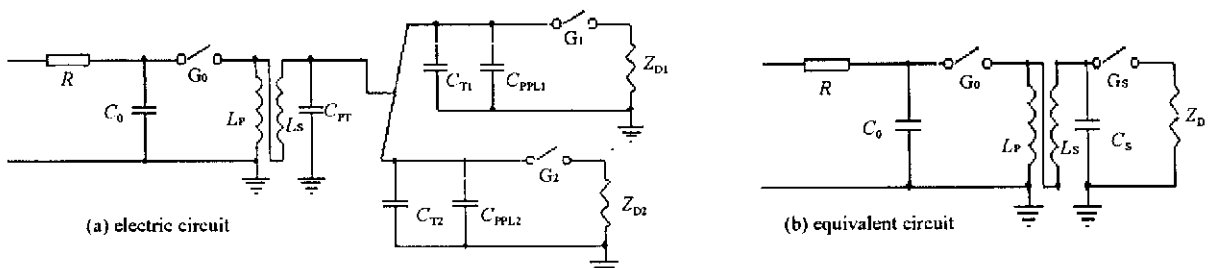


Fig. 4 Schematic of the electric circuit ( a ) and the equivalent circuit of the electron beams generator ( b )

For  $2\text{m}$  oil transmission line (  $\epsilon_r = 2.3$  ) , its capacitance is  $0.56\text{nF}$  , thus  $C_{T1} = C_{T2} = C_T/2 = 0.28\text{nF}$ . For the transformer windings , the capacitance between the innermost two turns of the coil is

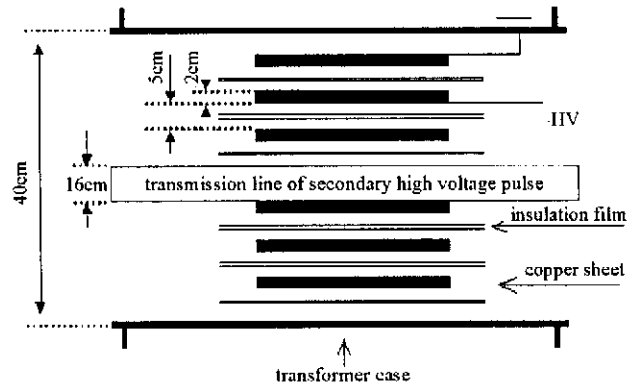


Fig. 3 Structure and the dimension of the pulsed transformer

Table 2 Available insulation films for the high voltage pulsed transformer

	dielectric constant	dielectric strength	dissipation factor
	at $1\text{MHz}$	$(\text{kV} \cdot \text{mm}^{-1})$	at $1\text{MHz}$
HDPE	2.34	37	$0.2 \times 10^{-3}$
PTFE	2.1	48	0.5
FET	2.1	24	0.5
PET	4.0	42	20

$$C_{T-T} = \frac{\varepsilon_r}{18} \frac{W_s}{\ln \frac{r_1 + \Delta r}{r_1}} = 0.9 \text{ nF} \quad (7)$$

thus , the series capacitance of the windings is

$$C_{PT} \approx \frac{1}{n+1} C_{T-T} = 0.06 \text{ nF} \quad (8)$$

and the total capacitance on the secondary side of the transformer is

$$C_s = C_{PFL1} + C_{PFL2} + C_{PT} + C_{TL1} + C_{TL2} = 16.9 \text{ nF} \quad (9)$$

and the equivalent circuit can be simplified as in Fig. 4( b ). For the 100% energy transfer from  $C_0$  to  $C_s$  ,  $L_p C_0 = L_s C_s$  and  $K = 0.6$  must be satisfied in the primary and secondary circuits in the double resonant charging model.

Thus , the capacitance of the primary energy storage capacitor(  $C_0$  ) is calculated to be  $C_0 \approx 1.4 \mu\text{F}$  from above condition and the resonant frequency in these two circuit loops is  $\omega = 1/(L_p C_0)^{1/2} = 1/(L_s C_s)^{1/2} = 1.5 \text{ MHz}$ . The voltage gain of the secondary side to the primary side is  $\alpha = V_s/V_p = (C_0/C_s)^{1/2} = (L_s/L_p)^{1/2} = 9$ . The voltage waveform on the secondary capacitor versus time is as<sup>[13,14]</sup>

$$V_s(t) = \frac{\alpha V_0}{2} \left[ \cos \frac{\omega t}{\sqrt{1-K}} - \cos \frac{\omega t}{\sqrt{1+K}} \right] \quad (10)$$

where ,  $V_0$  is the primary voltage on  $C_0$ . The normalized output voltage waveform is shown in Fig. 5. We can see that the charging waveform inverts the time  $t_1 = 1.77 \text{ ms}$  and reaches the maximum value on  $C_s$  at  $t_2 = 2.65 \text{ ms}$ . The rise-time of the voltage pulse from  $t_1$  to  $t_2$  is  $880 \text{ ns}$ .

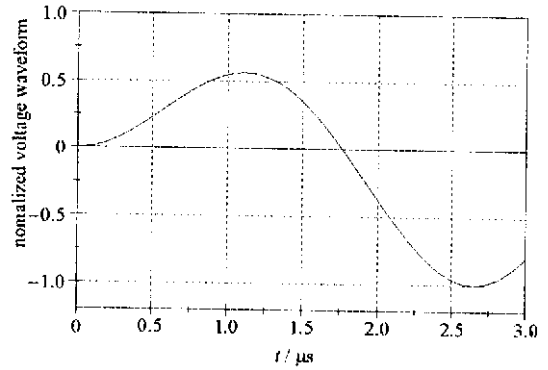


Fig. 5 Normalized charging voltage waveform on the secondary capacitor vs the charging time

## 5 Conclusion

In the double resonant charging model , the effective charging time is  $0.88 \mu\text{s}$ . It is short enough for the de-ionized water-filled pulse forming line. With the pulse transformer , the voltage gain is 9. The transformer windings have enough capacitance to prevent the coil from electrical breaking. If the coefficient of the energy from the electricity to laser is  $3.3\%$ <sup>[15]</sup> , the output energy of HF/DF laser can reach to  $250 \text{ J}$  at  $3.8 \mu\text{m}$ . The high-energy laser can run at  $1 \text{ Hz}$  repetition-rate.

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## 用于泵浦非链式 HF/DF 化学激光器的重复频率电子束发生器研究

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摘 要 : 正在研究的 1Hz 重复频率电子束泵浦 HF/DF 化学激光器 , 预期产生的电子束能量为 0.5MeV、束流强度为 100kA、束流脉冲宽度为 100ns。在该系统设计中 , 使用了一个脉冲变压器来对脉冲成形水线进行双共振充电。脉冲变压器的初级、次级电感与互感分别为 331nH、26.5 $\mu$ H 与 1.9 $\mu$ H。脉冲成形线的电容、电感与阻抗分别为 8.15nF、300nH 与 6.2 $\Omega$ 。脉冲成形线在 1MV 的峰值充电电压下的击穿因子为 0.3。在 3.3% 的能量转换效率条件下 , 预期可以产生的 HF/DF 激光脉冲能量为 250J 以上。

关键词 : 重复频率电子束发生器 ; HF/DF 化学激光器 ; 脉冲变压器